AMENDMENTS TO THE CLAIMS

1. (Withdrawn) A microfluidic device, comprising

a substrate;

a plurality of resin layers formed on the substrate; and

a three-dimensional fluid circuit formed in the plurality of the resin layers.

2. (Currently Amended) A method of manufacturing a microfluidic device, comprising the steps of:

(a) ~~forming~~ laminating a resin ~~layer~~ film on a substrate, and forming a groove having a predetermined pattern which functions as a fluid flow path by removing a part of the resin film layer by laser processing;

(b) ~~forming~~ laminating a subsequent resin film ~~layer by coating a resin~~ on the overall surface of ~~the~~ said resin film layer having been processed, and forming a groove in the subsequent resin film layer by laser processing and/or forming, by laser processing of the subsequent resin film layer, a throughhole to the groove formed in ~~the~~ said resin film layer having been processed ~~coated with the resin, by laser processing of the subsequent resin layer~~;

(c) repeating the step (b); and

(d) forming a three-dimensional fluid circuit by finally forming inlets and an outlet by ~~resin coating~~ laminating a resin film.

3. (Cancelled)

4. (Cancelled)

5. (New) The method of manufacturing the microfluidic device according to claim 2, wherein the thickness of the resin film layer is 10 to 1000 μm.

6. (New) The method of manufacturing the microfluidic device according to claim 2, wherein the depth of the groove is 20 to 30 μm.

7. (New) The method of manufacturing the microfluidic device according to claim 2, wherein the width of the groove is 20 to 100 μm.